

FORM PTO-1449 (Rev. 2-32) U.S. Department of Commerce Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Atty. Docket No. 03-06	Serial No.
	Applicant: Harry Levinson and Thomas White	
	Filing Date: January 12, 2004	Group:

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc).

			A. Mikkelsen et al., <i>EUVL Mask Flatness and Electrostatic Chucking Analysis</i> , Presented at the 47 th International Conference on Electron, Ion and Photon Beam Technology and Nanofabrication (Tampa, FL) and submitted to the <i>Journal of Vacuum Science and Technology B</i> , Nov/Dec, 2003

EXAMINER Danny Nguyen	DATE CONSIDERED 8/7/06
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